

**Notice of References Cited**

Application/Control No.

09/835,643

Applicant(s)/Patent Under  
Reexamination  
AHN ET AL.

Examiner

Leonardo Andújar

Art Unit

2826

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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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	C	US-			
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**FOREIGN PATENT DOCUMENTS**

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	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Spigel et al., Impact of Light Illumination and Passivation Layer on Silicon Finite Ground Coplanar Waveguide Transmission Line Properties, October 2000, IEE Transaction on Microwave Theory and Techniques, Volume 48, NO. 10, pages 1673-1679.
	V	Yang et al., Characteristics of Trenched Coplanar Waveguide for High Resistivity Si MMIC Applications, May 1998, IEE Transaction on Microwave Theory and Techniques, Volume 46, NO. 05, pages 623-631.
	W	Hu et al., Characteristics of Trenched Coplanar Waveguide for Si MMIC Applications, June 1997, IEE MTT-Digest, pages 735-738.
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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